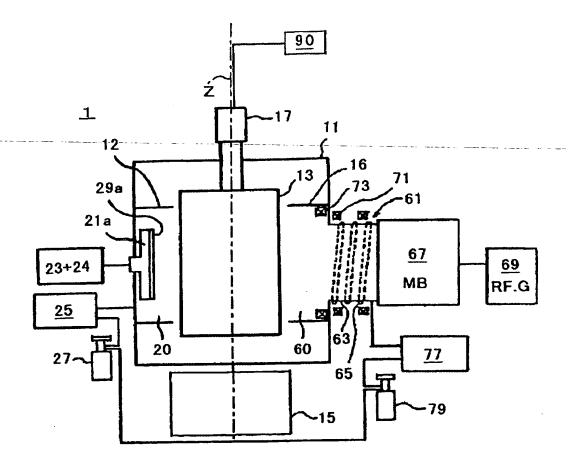
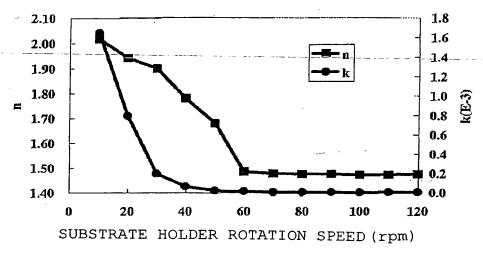


[図2]



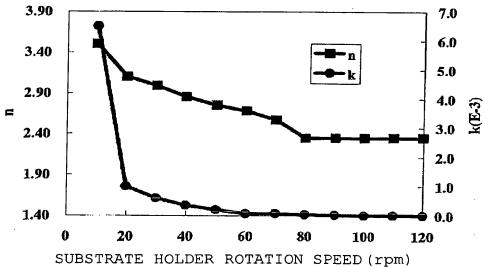
[図3]

DEPENDENCE OF OPTICAL CHARACTERISTIC OF THIN FILM ON SUBSTRATE HOLDER ROTATION SPEED

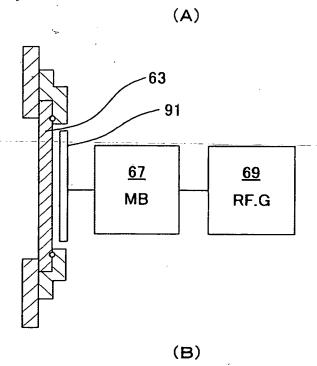


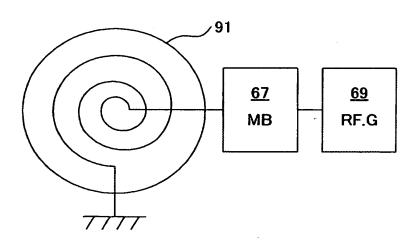
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DEPENDENCE OF OPTICAL CHARACTERISTIC OF THIN FILM ON SUBSTRATE HOLDER ROTATION SPEED

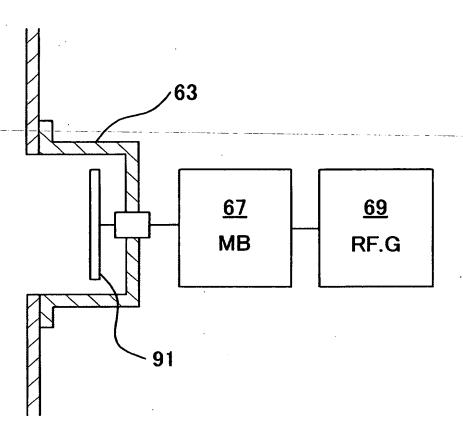


[図5]

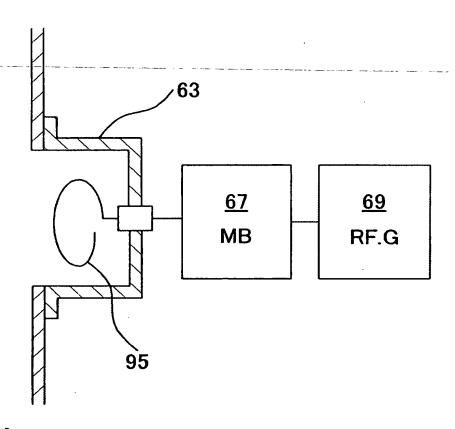




[図6]

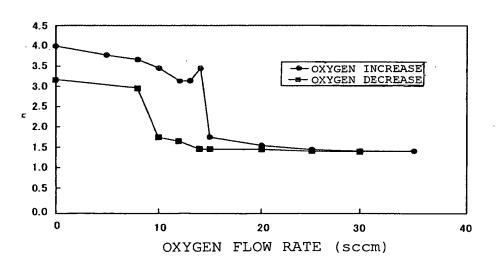


[図7]



[図8]

DEPENDENCE OF REFRACTIVE INDEX OF THIN FILM ON OXYGEN FLOW RATE (USUAL REACTION SPUTTERING)



[図9]

DEPENDENCE OF DECAY COEFFICIENT OF THIN FILM ON OXYGEN FLOW RATE

(USUAL REACTION SPUTTERING)

